



PATENT APPLICATION B1/HK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yukio MIYAIRI et al.

Group Art Unit: 1795

Application No.: 10/561,841

Examiner: K. MAYEKAR

Filed: December 22, 2005

Docket No.: 126400

For: PLASMA GENERATING ELECTRODE AND PLASMA REACTOR

SUBMISSION OF REFERENCES

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

It is respectfully requested that the following references be placed in the Patent Office file regarding the above-identified application.

1. An English language Abstract of one or more non-English language reference is attached. See References 1 & 2.

2. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 1 & 2.

Respectfully submitted,

James A. Oliff
Registration No. 27,075

Andy N. Kim
Registration No. 61,050

JAO:ANK/mjb

Date: April 23, 2010

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
Deposit Account No. 15-0461